

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicant(s):** Huilong Zhu, et al.

**Examiner:** Chuong A. Luu

**Serial No:** 10/709,239

**Art Unit:** 2818

**Filed:** April 23, 2004

**Docket:** FIS920030375US1 (17192)

**For:** STRUCTURES AND METHODS FOR  
MANUFACTURING OF DISLOCATION  
FREE STRESSED CHANNELS IN BULK  
SILICON AND SOI CMOS DEVICES BY  
GATE STRESS ENGINEERING WITH  
SiGe AND/OR Si:C

**Dated:** October 26, 2006

**Confirmation No:** 3238

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

**AMENDMENT**

Sir:

In connection with filing the above-identified application under 37 C.F.R. §1.53(b), applicants submit the following amendments and remarks for consideration by the Examiner and entry of record in the above-identified patent application.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.

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**CERTIFICATE OF ELECTRONIC FILING**

I hereby certify that this correspondence is being deposited with the United States Patent & Trademark Office via Electronic Filing through the United States Patent and Trademark Office e-business website, on October 26, 2006.

Dated: October 26, 2006



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Steven Fischman